

## **RESPONSE UNDER 37 CFR 1.116 EXPEDITED PROCEDURE EXAMINING GROUP 1765**

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

KIRIMURA et al.

Filed: April 2, 2001

Application No.: 09/822,414

FILM FORMING APPARATUS AND METHOD OF FORMING A CRYSTALLINE For:

Art Unit: 1765

Examiner: M. Song

Attorney Dkt. No.: 107351-00011

SILICON FILM

AMENDMENT AFTER RECONSIDERATION AFTER FINAL REJECTION

**BOX AF** 

Commissioner for Patents P.O. Box 1450 Arlington, VA 22313-1450

May 27, 2003

Sir:

In reply to the outstanding Office Action dated February 26, 2003, (with May 26,

2003 being a holiday), please amend the above-identified patent application as follows: